

Kazuki Denpoh

List of Publications by Year in descending order

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23
papers

337
citations

1163117
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23
all docs

23
docs citations

23
times ranked

195
citing authors

#	ARTICLE	IF	CITATIONS
1	Self-consistent particle simulation of radio-frequency CF4 discharge with implementation of all ion-neutral reactive collisions. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 1998, 16, 1201-1206.	2.1	100
2	Self-Consistent Particle Simulation of Radio Frequency CF4 Discharge: Effect of Gas Pressure. Japanese Journal of Applied Physics, 2000, 39, 2804-2808.	1.5	66
3	Monte Carlo Collision Simulation of Positive-Negative Ion Recombination for a Given Rate Constant. Journal of the Physical Society of Japan, 1998, 67, 1288-1290.	1.6	35
4	Sheath Model for Dual-Frequency Capacitively Coupled Plasmas. Japanese Journal of Applied Physics, 2004, 43, 5533-5539.	1.5	19
5	Simulation of ion energy and angular distribution functions using Monte Carlo method coupled with multidimensional radio frequency sheath model developed utilizing COMSOL Multiphysics. Japanese Journal of Applied Physics, 2014, 53, 080304.	1.5	14
6	Multiscale plasma and feature profile simulations of plasma-enhanced chemical vapor deposition and atomic layer deposition processes for titanium thin film fabrication. Japanese Journal of Applied Physics, 2020, 59, SHHB02.	1.5	14
7	Computational study on silicon oxide plasma enhanced chemical vapor deposition (PECVD) process using tetraethoxysilane/oxygen/argon/ helium. Japanese Journal of Applied Physics, 2019, 58, SEED06.	1.5	11
8	Observation and evaluation of flaked particle behavior in magnetically enhanced reactive ion etching equipment using a dipole ring magnet. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2004, 22, 1688.	1.6	10
9	Modification of Semianalytical Finite Element Model for Radio Frequency Sheaths in Single- and Dual-Frequency Capacitively Coupled Plasmas: Incorporating Ion Density Oscillation at Low Frequency. Japanese Journal of Applied Physics, 2010, 49, 056202.	1.5	8
10	Dissociative reactions induced by electron impact and electron transport in TEOS vapor. Japanese Journal of Applied Physics, 2019, 58, 066003.	1.5	8
11	Ion energy control and its applicability to plasma enhanced atomic layer deposition for synthesizing titanium dioxide films. Thin Solid Films, 2018, 660, 865-870.	1.8	7
12	Semianalytical Finite Element Method Model for Radio Frequency Sheaths in Single- and Dual-Frequency Capacitively Coupled Plasmas. Japanese Journal of Applied Physics, 2009, 48, 090209.	1.5	6
13	Particle-in-Cell/Monte Carlo Collision Simulations of Striations in Inductively Coupled Plasmas. Japanese Journal of Applied Physics, 2012, 51, 106202.	1.5	6
14	Impact of ion energies in Ar/H2 capacitively coupled radio frequency discharges on PEALD processes of titanium films. Surface and Coatings Technology, 2018, 350, 740-744.	4.8	6
15	Effects of driving frequency on plasma density in Ar and H ₂ /Ar capacitively coupled plasmas at Torr-order pressure. Japanese Journal of Applied Physics, 2021, 60, 016002.	1.5	6
16	Particle-in-Cell/Monte Carlo Collision Simulations of Striations in Inductively Coupled Plasmas. Japanese Journal of Applied Physics, 2012, 51, 106202.	1.5	6
17	Theoretical Study on the Angular Distribution of Molecular Flux Effusing into a Vacuum.. 880-02 Nihon Kikai Gakkai Ronbunshu Transactions of the Japan Society of Mechanical Engineers Series B B-hen, 1993, 59, 101-108.	0.2	4
18	Another Possible Origin of Temperature and Pressure Gradients across Vane in the Crookes Radiometer. Journal of the Vacuum Society of Japan, 2017, 60, 471-474.	0.3	3

#	ARTICLE	IF	CITATIONS
19	Quasi-Nanbu Scheme and a DSMC Model Created on COMSOL Multiphysics. <i>Vacuum and Surface Science</i> , 2019, 62, 318-323.	0.1	3
20	Modification of Semianalytical Finite Element Model for Radio Frequency Sheaths in Single- and Dual-Frequency Capacitively Coupled Plasmas: II. Effects of Nonuniform Bulk Plasma Density and Charging at Dielectric Surface. <i>Japanese Journal of Applied Physics</i> , 2011, 50, 036001.	1.5	2
21	Modification of Semianalytical Finite Element Model for Radio Frequency Sheaths in Single- and Dual-Frequency Capacitively Coupled Plasmas: II. Effects of Nonuniform Bulk Plasma Density and Charging at Dielectric Surface. <i>Japanese Journal of Applied Physics</i> , 2011, 50, 036001.	1.5	2
22	Quasi-Nanbu Scheme Extended to Diatomic Molecules and Gas Mixtures. <i>Vacuum and Surface Science</i> , 2021, 64, 294-300.	0.1	1
23	Semi-analytical model for a static sheath including a weakly collisional presheath. <i>Japanese Journal of Applied Physics</i> , 2018, 57, 06JG02.	1.5	0